

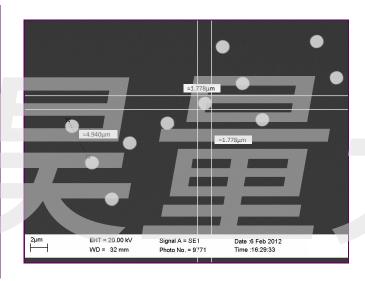


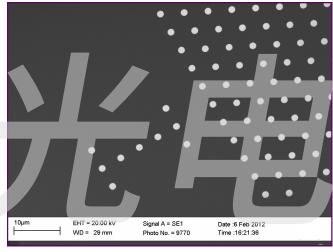
## NORCADA MICROPOROUS LOCATION-TAGGED TEM DEVICES

## **Features**

- 1.8μm Holes 5μm pitch
- · Silicon Nitride film with microporous pattern and tagged locations
- The film is mechanically robust and is fabricated in 50nm thicknesses
- · These devices can be used in high beam intensity TEM
- Part Number: NH050A2

NANOTECHNOLOGY & MICROSCOPY





## **Applications**

The advantage of these membranes is that the films will provide a supportive platform for overhanging samples that lay across the micropores.

A string-shaped material can be placed or grown overhanging across the holes. This allows for having no thin film background for the microscopy image.

These membranes have many applications in high resolution TEM, STEM and STXM.

